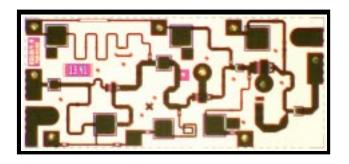


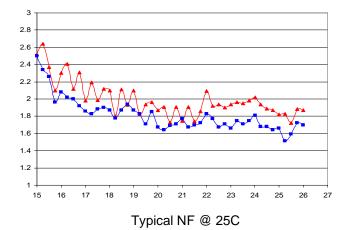
Ka Band Low Noise Amplifier

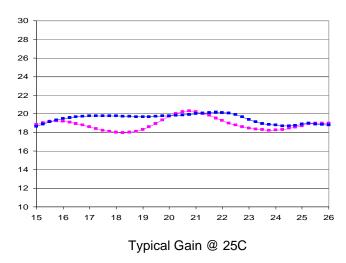
TGA1319A-EPU



Chip Dimensions 1.984 mm x .923 mm

Preliminary Data, 2 Fixtured samples @ 25C



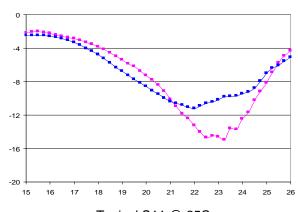


Key Features and Performance

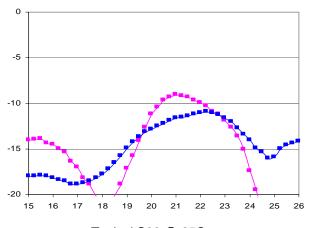
- 0.15um pHEMT Technology
- 21-27 GHz Frequency Range
- 2 dB Nominal Noise Figure
- 19 dB Nominal Gain
- 12 dBm Pout
- 3V, 45 mA with -0.5V < Vg < +0.5V

Primary Applications

- Point-to-Point Radio
- Point-to-Multipoint Communications



Typical S11 @ 25C



Typical S22 @ 25C

Note: Devices designated as EPU are typically early in their characterization process prior to finalizing all electrical and process specifications. Specifications subject to change without notice



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MAXIMUM RATINGS

SYMBOL	PARAMETER <u>4</u> /	VALUE	NOTES
V ⁺	POSITIVE SUPPLY VOLTAGE	5 V	
\mathbf{I}^{+}	POSITIVE SUPPLY CURRENT	60 mA	1/
I-	NEGATIVE GATE CURRENT	5.28 mA	
P_{IN}	INPUT CONTINUOUS WAVE POWER	15 dBm	
P_{D}	POWER DISSIPATION	.3 W	
T_{CH}	OPERATING CHANNEL TEMPERATURE	150 °C	<u>2</u> / <u>3</u> /
T_{M}	MOUNTING TEMPERATURE (30 SECONDS)	320 °C	
T_{STG}	STORAGE TEMPERATURE	-65 to 150 °C	

- 1/ Total current for all stages.
- 2/ These ratings apply to each individual FET.
- $\underline{3}$ / Junction operating temperature will directly affect the device median time to failure (T_M). For maximum life, it is recommended that junction temperatures be maintained at the lowest possible levels.
- 4/ These ratings represent the maximum operable values for the device.

DC PROBE TESTS
$$(T_A = 25 \text{ °C} \pm 5 \text{ °C})$$

Symbol	Parameter	Minimum	Maximum	Value
Idss	Saturated Drain Current			mA
V_{P}	Pinch-off Voltage	-1.5	-0.5	V
BVGS	Breakdown Voltage gate-source			V
BVGD	Breakdown Voltage gate-drain			V

ON-WAFER RF PROBE CHARACTERISTICS

$$(T_A = 25 \text{ °C} \pm 5 \text{ °C})$$

 $V_d = 3 \text{ V}, I_{d1} = 15 \text{ mA}, I_{d2} = 30 \text{ mA}$

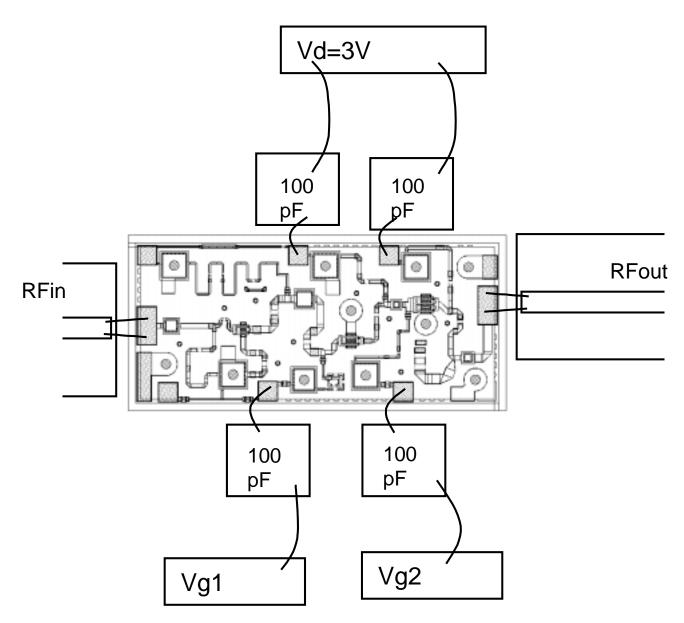
Symbol	Parameter	Test Condition	Limit			Units
			Min	Тур	Max	
Gain	Small Signal Gain	F = 21 - 27 GHz	18			dB
NF	Noise Figure	F = 21 - 26.5 GHz			2	dB
PWR	Output Power @ P1dB	F = 21 - 27 GHz	10			dBm





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Notes: 1. Vg1 and Vg2 may be sourced from the same supply.

2. Positive or negative gate bias may be required to achieve recommended operating point.

TGA1319A - Recommended Assembly Drawing

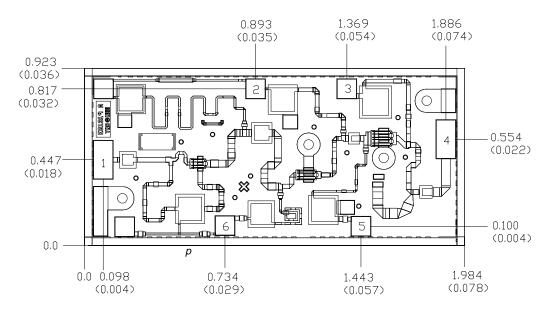
Note: Devices designated as EPU are typically early in their characterization process prior to finalizing all electrical and process specifications. Specifications subject to change without notice



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Units: millimeters (inches) Thickness: 0.1016 (0.004)

Chip edge to bond pad dimensions are shown to center of bond pad Chip size tolerance: +/- 0.051 (0.002)

Bond	Pad	#1	(RF Input)	0.100	×	0.200	(0.004	×	0.008)
Bond	Pad	#2	(Vd1)	0.100	×	0.100	(0.004	×	0.004)
Bond	Pad	#3	(Vd2)	0.100	×	0.100	(0.004	×	0.004)
Bond	Pad	#4	(RF Dutput)	0.100	×	0.200	(0.004	×	0.008)
Bond	Pad	#5	(Vg2)	0.100	×	0.100	(0.004	×	0.004)
Bond	Pad	#6	(Vg1)	0.100	×	0.100	(0.004	×	0.004)

Mechanical Drawing



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Assembly Process Notes

Reflow process assembly notes:

- Use AuSn (80/20) solder with limited exposure to temperatures at or above 300 °C.
- An alloy station or conveyor furnace with reducing atmosphere should be used.
- No fluxes should be utilized.
- Coefficient of thermal expansion matching is critical for long-term reliability.
- Devices must be stored in a dry nitrogen atmosphere.

Component placement and adhesive attachment assembly notes:

- Vacuum pencils and/or vacuum collets are the preferred method of pick up.
- Air bridges must be avoided during placement.
- The force impact is critical during auto placement.
- Organic attachment can be used in low-power applications.
- Curing should be done in a convection oven; proper exhaust is a safety concern.
- Microwave or radiant curing should not be used because of differential heating.
- Coefficient of thermal expansion matching is critical.

Interconnect process assembly notes:

- Thermosonic ball bonding is the preferred interconnect technique.
- Force, time, and ultrasonics are critical parameters.
- Aluminum wire should not be used.
- Discrete FET devices with small pad sizes should be bonded with 0.0007-inch wire.
- Maximum stage temperature is 200 °C.

GaAs MMIC devices are susceptible to damage from Electrostatic Discharge. Proper precautions should be observed during handling, assembly and test.